



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : István Endre LUKÁCS et al. ) Group Art Unit: 2877  
Appln. No. : 10/814,252 ) Examiner: S. Nguyen  
Filed : April 1, 2004 ) Confirmation No.: 6976  
For : APPARATUS AND MEASUREMENT PROCEDURE FOR THE FAST,  
QUANTITATIVE, NON-CONTACT TOPOGRAPHIC INVESTIGATION OF  
SEMI-CONDUCTOR WAFERS AND OTHER MIRROR LIKE SURFACES

**RESPONSE UNDER 37 C.F.R. 1.112**

Commissioner for Patents  
U.S. Patent and Trademark Office  
Customer Service Window, Mail Stop Amendment  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir:

Responsive to the Office Action of July 14, 2005, the period for response extending until October 14, 2005, reconsideration of this action and allowance of all the claims of the present application are respectfully requested and are now believed appropriate in view of the following remarks.

**Remarks** begin on page 2 of this paper.